ABSTRACT

The present invention relates to a substrate carrying device that carries a substrate such as a reticle, a substrate carrying method thereof, and an exposure device thereof. An object of the present invention is to securely suck a substrate onto a lower surface of a chuck.

The present invention is a substrate carrying device including a movable stage having a chuck and being movable in a horizontal direction, the chuck having a sucking surface which faces downward and sucking a substrate on the sucking surface; and a fixed blind disposed below the movable stage. The movable stage moves to a position apart from the fixed blind in a horizontal direction and attaches and detaches the substrate. In addition, the substrate carrying device also includes a lifting portion having a lifting table which is movable in a movable range of the movable stage and is capable of being positioned below the movable stage; and a carrying portion having a carrying arm which carries the substrate to the lifting portion.